ABSTRACT OF THE DISCLOSURE

A method and apparatus providing a micro-mirror device configured to increase a switching frequency thereof. The micro-mirror device includes a substrate with at least one address electrode positioned over the substrate to provide an electrostatic force and includes at least one support member positioned over the substrate and extending upward above the substrate. The micro-mirror device also includes a mirror and a spring member. The mirror is disposed over the at least one address electrode and coupled to the at least one support member. The mirror is configured to deflect toward the substrate in response to the at least one address electrode applying the electrostatic force to the mirror. The spring member is spaced apart between the substrate and the mirror and coupled to the at least one support member. The spring member is operable to deflect separately from the mirror and toward the substrate.